EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	17685	b23k026$.ipc.	JPO	OR	ON	2006/08/05 09:37
L2	146	L1 and (curv$5 with (hold$3 support$3 chuck$3 table bed surface))	JPO	OR	ON	2006/08/05 09:38
L3	129	L2 and laser	JPO	OR	ON	2006/08/05 09:37
L4	1104	L1 and ((curv$5 arcuate arc round$3 spher$7 shape$2) with (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and laser	JPO	OR	ON	2006/08/05 11:00
L5	776	L1 and ((curv$5 arcuate arc round$3 spher$7 shape$2) with (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and ((curv$5 arcuate arc round$3 spher$7 shape$2) with laser)	JPO	OR	ON	2006/08/05 09:44
L6	325	L1 and ((curv$5 arcuate arc round$3 spher$7 shape$2) near3 (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and ((curv$5 arcuate arc round$3 spher$7 shape$2) with laser)	JPO	OR	ON	2006/08/05 09:45
L7	116	L1 and ((curv$5 arcuate arc round$3 spher$7) near3 (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and ((curv$5 arcuate arc round$3 spher$7 shape$2) with laser)	JPO	OR	ON	2006/08/05 09:45
L8	105	L1 and ((curv$5 arcuate arc round$3 spher$7) near3 (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and ((curv$5 arcuate arc round$3 spher$7) with laser)	JPO	OR	ON	2006/08/05 09:46
L9	98	L1 and ((curv$5 arcuate arc round$3 spher$7) near3 (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and ((curv$5 arcuate arc round$3 spher$7) with laser) not (arc adj weld$4) not (arc adj discharg$5)	JPO	OR	ON	2006/08/05 10:37
L11	2	"20040155019"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 10:38

L12	1	11 and (focal adj length) with condenser with curvature	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 10:42
L15	1	11 and y with x	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 10:46
L17	1	11 and y	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 10:55
L18	9	(("5643826") or ("6246524") or ("6137633") or ("6176926") or ("6104535") or ("6304385") or ("6300176") or ("5858822") or ("6077731")).PN.	USPAT; USOCR	OR	OFF	2006/08/05 10:56
L19	8	18 and stage	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 11:34
L20	3	18 and stage with (curv$7 arcuate cylind$6 spher$7)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 11:00
L21	10	L1 and ((curv$5 arcuate arc round$3 spher$7 shape$2) with (hold$3 support$3 chuck$3 table bed surface stage clamp$3)) and laser and anneal$5	JPO	OR	ON	2006/08/05 11:04
L22	20	L1 and ((curv$5 arcuate arc round$3 spher$7 shape$2)) and laser and anneal$5 not 21	JPO	OR	ON	2006/08/05 11:10
L23	68	L1 and ((curv$5 arcuate arc round$3 spher$7 shape$2) with (silicon wafer semiconductor))	JPO	OR	ON	2006/08/05 11:11
L24	5	L1 and ((curv$5 arcuate arc round$3 spher$7) with (silicon wafer semiconductor))	JPO	OR	ON	2006/08/05 11:12
L25	13	L1 and ((bend$4 bent warp$4) with (silicon wafer semiconductor))	JPO	OR	ON	2006/08/05 11:29

EAST Search History

L26	4	L1 and (concav$5 with (silicon wafer semiconductor))	JPO	OR	ON	2006/08/05 11:31
L27	3	L1 and (concav$5 and (silicon wafer semiconductor)) not 26	JPO	OR	ON	2006/08/05 11:32
L28	1620	(concav$5 with (silicon wafer semiconductor)) same (stage support$4 platform hold holding holder)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 11:35
L29	869	(silicon wafer semiconductor) same (stage support$4 platform hold holding holder) near5 concav$5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 11:35
L30	29	(silicon wafer semiconductor) same (stage support$4 platform hold holding holder) near5 concav$5 same (warp$4 bend$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:19
L34	117	(silicon wafer semiconductor) same anneal$4 and ((stage support$4 platform hold holding holder) near5 concav$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:20
L35	95	(silicon wafer semiconductor) with anneal$4 and ((stage support$4 platform hold holding holder) near5 concav$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:20
L36	4	(silicon wafer semiconductor) with anneal$4 and ((stage support$4 platform hold holding holder) near5 concav$5 same laser)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:22
L37	0	(silicon wafer semiconductor) same anneal$4 same ((stage support$4 platform hold holding holder) near5 concav$5 same laser)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:23
L38	5	(silicon wafer semiconductor) same anneal$4 and ((stage support$4 platform hold holding holder) near5 concav$5 same laser)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:24
L39	112	(silicon wafer semiconductor) same anneal$4 and ((stage support$4 platform hold holding holder) near5 concav$5) not 38	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:24

EAST Search History

L40	5	(silicon wafer semiconductor) same anneal$4 same ((stage support$4 platform hold holding holder) near5 concav$5) not 38	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:29
L41	28453	"269"/$.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:29
L42	27	41 and concav$4 with (wafer silicon)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:38
L43	9256	(wafer silicon) same (lithograph$5 pattern fabrication) same (anneal$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:39
L44	725	(wafer silicon) same (lithograph$5 pattern fabrication) same (anneal$4) same (chuck stage table support)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:40
L45	5	(wafer silicon) same (lithograph$5 pattern fabrication) same (anneal$4) same (chuck stage table support) same (concav$4 convex$4 cylindrical$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:47
L46	205	(wafer silicon) same (lithograph$5 pattern fabrication) same (anneal$4) and ((chuck stage table support) same (concav$4 convex$4 cylindrical$4)) not 45	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:47
L47	13	(wafer silicon) same (lithograph$5 pattern fabrication) same (anneal$4) and ((chuck stage table support) same (concav$4 convex$4 cylindrical$4) same anneal$4) not 45	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:52
L48	18	(wafer silicon) with laser with (anneal$4) and ((chuck stage table support) same (concav$4 convex$4 cylindrical$4) with anneal$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:53
L49	1	("5907770").PN.	USPAT; USOCR	OR	OFF	2006/08/05 12:54

EAST Search History

L51	1	49 and (concav$4 convex$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 12:55
L52	1	49 and (concav$4 convex$4) with stage	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 13:00
L53	1	18 and (concav$4 convex$4) with stage	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 13:01
L54	0	18 and concav$4 with stage	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/05 13:01